

INTERFEROMETRIC SYSTEM FOR  
PRECISION IMAGING OF VIBRATING STRUCTURES

Abstract of the Disclosure

5        An optical profiler is modified in a way which allows it to  
image a MEMS device at various points during the movement of the  
MEMS device. The light source is synchronized with a desired  
movement of the MEMS device. The light source produces pulse at  
each synchronization period. During each pulse, an  
10        interferometric measurement is carried out. So long as the pulse  
is short enough such that the device does not move significantly,  
a detection of the position of the device can be accurately  
obtained.